



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of : **Confirmation No. 4508**

Toshifumi KIMBA et al. : Docket No. 2000-1706A

Serial No. 09/734,737 : Group Art Unit 2877

Filed December 13, 2000 : Examiner Hoa Q. Pham

SUBSTRATE FILM THICKNESS
MEASUREMENT METHOD, SUBSTRATE
FILM THICKNESS MEASUREMENT
APPARATUS AND SUBSTRATE
PROCESSING APPARATUS

THE COMMISSIONER IS AUTHORIZED
TO CHARGE ANY DEFICIENCY IN THE
FEE FOR THIS PAPER TO DEPOSIT
ACCOUNT NO. 23-0975.

AMENDMENT AFTER FINAL

RESPONSE UNDER 37. CFR 1.116
EXPEDITED PROCEDURE
EXAMINING GROUP 2877.

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Responsive to the Office Action of November 19, 2003, a Petition for a one month extension of time being filed concurrently herewith, please amend the above-identified application as follows.